Surface and Interface Scattering

Dillon Fong (fong@anl.gov) Materials Science Division Argonne National Laboratory Intro

Surface x-ray diffraction (SXRD, SXS, GIXS, GIXD, ...)



Surface x-ray diffraction (SXRD, SXS, GIXS, GIXD, ...)



Intro

Motiv

on: Watch materials creation

Intro



- atomic structure (SXRD)
- occupied electronic levels (HAXPES)
- unoccupied electronic levels (XANES)
- band structure (HARPES)



H. Zhou et al., PNAS 107, 8103 (2010).



T.C. Rödel et al., Phys. Rev. Appl. 1, 051002 (2014).

Intro

Motivation: Watch materials creation & property evolution during creation





Binding Energy (eV)

electronic structure





Motivation: Watch surfaces during reaction

heterogeneous catalysis, APS Sector 12

Intro





Example from APS Sector 12

$PbTiO_3/SrTiO_3(001)$

- can look at 3D atomic resolution structure (like TEM)
- but can look at non-destructively





D. D. Fong et al. Phys. Rev. B 71, 144112 (2005)

I. Surface X-ray Diffraction (SXRD)

- Modeling F(Q)
 - Structure factor for a crystal
 - Structure for a film / substrate
 - Effect of roughness
 - Fitting examples
- Why model? Can understand what SXRD is good for
- I will assume you are all working on epitaxial heterostructures...

II. Direct methods

III. Example results

IV. Practicalities

V. X-ray photon correlation spectroscopy (XPCS)

SXRD geometry

I often work with (001) crystals



T.T. Fister & D. D. Fong in Thin Film Metal-Oxides, Springer (2010)

Modeling F(Q) for a CTR

Ex. PbTiO₃ / SrTiO₃ (001)

$$F_{\text{CTR}}(\mathbf{Q}) = N_1 N_2 F_{\text{column}}(\mathbf{Q})$$

$$F_{\text{column}}(\mathbf{Q}) = \sum_{n=0}^{\infty} F_n^{\text{unit cell}}(\mathbf{Q}) e^{-n(iQ_z d_n)}$$

= geometric series: $a + ar + ar^2 + ar^3 + ...$

Example geom series: {1, 1/2, 1/4, 1/8, 1/16, 1/32, ...}

What is the sum over the first 6 terms?

a = I (first term)

N = 6 terms

Useful formulas for CTRs:

$$\sum_{n=0}^{N-1} ar^n = a\left(\frac{1-r^N}{1-r}\right)$$

= 1.96875

 $\sum_{n=0}^{\infty} ar^n = a\left(\frac{1}{1-r}\right)$

= 2

Pb

Ti

 $\bigcirc \bigcirc$

Sr

•

n=0

n=1

We will use both of these expressions for film and substrate

Dillon Fong



 \boldsymbol{a}

N

Modeling F(Q) for a CTR

Ex. PbTiO₃ / SrTiO₃ (001)

film
$$a = F_{\text{film}}^{\text{unit cell}}$$
substrate $a = F_{\text{sub}}^{\text{unit cell}}$ $r = e^{-iQ_z c}$ $r = e^{-iQ_z a}$ $r = e^{-iQ_z a}$ $N =$ number of film unit cells $N = \infty$

Modeling F(Q) for a CTR

Ex. PbTiO₃ / SrTiO₃ (001)

$$F_{\text{CTR}}(\mathbf{Q}) = N_1 N_2 F_{\text{column}}(\mathbf{Q})$$
$$F_{\text{column}}(\mathbf{Q}) = \sum_{n=0}^{\infty} F_n^{\text{unit cell}}(\mathbf{Q}) e^{-n(iQ_z d_n)}$$
$$= \text{geometric series: } a + ar + ar^2 + ar^3 + ar^$$

• Pb
$$n=0$$

• Ti $n=1$
• O $n=2$
• Sr $n=3$
 $n=4$
 $n=5$
• $n=5$
• $n=2$
• $n=5$
• $n=3$
• n

$$F_{\text{column}}(\mathbf{Q}) = F_{\text{PbTiO}_{3}}^{\text{unit cell}}(\mathbf{Q}) \left(\frac{1 - e^{-iNQ_{z}c}}{1 - e^{-iQ_{z}c}}\right)$$
$$+ e^{-iQ_{z}((N-1)c + \xi)} F_{\text{SrTiO}_{3}}^{\text{unit cell}}(\mathbf{Q}) \frac{1}{1 - e^{-iQ_{z}a}}$$
interface phase factor

and the second second second second

Modeling F(Q) for a CTR + absorption

Ex. PbTiO₃ / SrTiO₃ (001)

$$F_{\text{CTR}}(\mathbf{Q}) = N_1 N_2 F_{\text{column}}(\mathbf{Q})$$

$$absorption$$

$$F_{\text{column}}(\mathbf{Q}) = \sum_{n=0}^{\infty} F_n^{\text{unit cell}}(\mathbf{Q}) e^{-n(iQ_z d_n + d_n/\zeta_n)}$$

$$F_{\text{column}}(\mathbf{Q}) = F_{\text{PbTiO}_3}^{\text{unit cell}}(\mathbf{Q}) \left(\frac{1 - e^{-iNQ_z c} e^{-Nc/\zeta_{\text{PbTiO}_3}}}{1 - e^{-iQ_z c} e^{-c/\zeta_{\text{PbTiO}_3}}} \right)$$

$$+ e^{-iQ_z((N-1)c+\xi)} e^{-((N-1)c+\xi)/\zeta_{\text{PbTiO}_3}} F_{\text{SrTiO}_3}^{\text{unit cell}}(\mathbf{Q}) \frac{1}{1 - e^{-iQ_z d} e^{-a/\zeta_{\text{SrTiO}_3}}}$$

where $\zeta_n = \lambda q_z / 4\pi \mu_n$

D. D. Fong and C. Thompson, Annu. Rev. Mater. Res. 36, 431 (2006)

Subsection

 $F_{\text{column}}(\mathbf{Q}) = F_{\text{PbTiO}_3}^{\text{unit cell}}(\mathbf{Q})$

Modeling F(Q) for a CTR + absorption

Don't forget the interface phase factor

Ex. PbTiO₃ / SrTiO₃ (001)



Section

Modeling F(Q) for a CTR + temperature effects + X-ray energy effects

Unit cell structure factor:

 $F_{\rm PbTiO_3}^{\rm unit\ cell}(\mathbf{Q}) =$

=

Atomic form factor:



$$\int_{j=1}^{N_{uc}} f_{j}(Q) e^{-B_{j}(Q/4\pi)^{2}} e^{i\mathbf{Q}\cdot\mathbf{R}_{j}}$$

$$f_{O(1)}(Q) e^{-B_{O(1)}(Q/4\pi)^{2}}$$

$$f_{O(2)}(Q) e^{-B_{O(2)}(Q/4\pi)^{2}} e^{iQ_{y}a/2} e^{iQ_{z}(\pm\delta z_{O(2)}-c/2)}$$

$$f_{O(2)}(Q) e^{-B_{O(2)}(Q/4\pi)^{2}} e^{iQ_{x}a/2} e^{iQ_{y}a/2} e^{iQ_{z}(\pm\delta z_{O(2)}-c/2)}$$

$$f_{Ti}(Q) e^{-B_{Ti}(Q/4\pi)^{2}} e^{iQ_{z}(\pm\delta z_{Ti}-c/2)}$$

$$f_{Pb}(Q) e^{-B_{Pb}(Q/4\pi)^{2}} e^{iQ_{x}a/2} e^{iQ_{y}a/2} e^{iQ_{z}(\pm\delta z_{Pb})}$$

$$f(Q,E) = f_0(Q) + f'(E) + if''(E)$$

see f0_WaasKirf.dat
based on Waasmaier-Kirfel model:
D.Waasmaier & A. Kirfel, Acta Cryst. A51, 416-413 (1995).

see http://henke.lbl.gov/optical_constants/sf/sf.tar.gz, from D.T. Cromer & D. Liberman, Acta Cryst. A37, 267 (1981) or http://www.tagen.tohoku.ac.jp/general/building/iamp/database/scm/AXS/ from Y. Waseda, Novel Application of Anomalous (Resonance) X-ray Scattering for Structural Characterization of Disordered Materials. New York. Springer. 1984

Modeling F(Q) for a CTR + temperature effects

Debye-Waller factors

need to look up in the literature
 e.g., isotropic Debye Waller factors

Table 5. Calculated temperature factors $B(\kappa)$, Å², for models 4, 5 and 6 compared with experimentally determined values for BaTiO₃.

Temperature (K)	Model	B(Sr)	B(Ti)	$B(O_1)$	<i>B</i> (O ₂)
100	4 (90)	0.199	0.135	0.194	0.402
	5 (90)	0.208	0.155	0.185	0.397
	6 (90)	0.228	0.194	0.195	0.399
300	4 (297)	0.492	0.251	0.278	0.807
	5 (297)	0.511	0.303	0.258	0.790
	6 (297)	0.526	0.352	0.275	0.783

for SrTiO₃: W. G. Stirling, J. Phys. C 5, 2711 (1972)

 Table 2. Summary of parameters refined at all temperatures (Pb at origin)

		11000	2500	55000
	-183°C	-115°C	25°C	220°C
Isotropic temp	perature factor refinem	nent		
$\delta z_{Ti}(\dot{A})$	0.167	0.171	0.162	0
$\delta z_{\alpha(i)}(\dot{A})$	0.492	0.479	0.473	0
$\delta z_{o(1)}(\dot{A})$	0.505	0.504	0.486	0
B(Pb)	0.378 (100)	0.757 (84)	0.706 (89)	2.711 (167)
B(Ti)	0.284 (215)	0.364 (187)	0.060 (170)	0.694 (225)
B[O(1)]	0.670 (140)	0.713 (123)	0.351 (117)	1.549 (102)
B[O(2)]	0.498 (98)	0.862 (85)	0.477 (75)	B[O(1)]
R	5.22	5.90	4.35	3.10
R	12.47	12.21	10.19	12.07
R _w	15.20	15.87	12.83	16.57

for PbTiO₃: A. M. Glazer & S. A. Mabud, Acta Cryst. B 34, 1065 (1978)





Watching @ 0 0 1/2 during homoepitaxy



Layer-by-layer growth: CTR intensity oscillates as individual monolayers nucleate and coalesce

Homoepitaxy vs heteroepitaxy



Modeling F(Q) for a CTR + continuous roughness

Continuous roughness

Gaussian distribution of step heights about a mean surface



the ideally flat surface.

J. Harada, Acta Cryst. A 48, 764 (1992)

Modeling F(Q) for a CTR + continuous + discrete roughness

Discrete roughness - more general

- can account for non-Gaussian thickness non-uniformity (e.g., bimodal distribution)
 - e.g., in PLD, for n pulses of (random) growth



Probability of getting exactly k layers to grow at unit cell position x after n pulses, with each pulse resulting in a coverage of p (i.e., binomial distribution)

$$P(X = k) = \binom{n}{k} p^{k} (1 - p)^{(n-k)} \text{ where } \binom{n}{k} = \frac{n!}{k!(n-k)!}$$

in our language
$$p = \text{coverage}, \theta \qquad R^{2} = \left[1 - 4\theta(1 - \theta)\sin^{2}(\pi L)\right]^{\frac{\sigma_{d}^{2}}{c^{2}\theta(1 - \theta)}}$$

$$n = \sigma_{d}^{2} / (c^{2} \theta(1 - \theta)) \qquad \text{D. Dale et al., Phys. Rev. B 74, 085419 (2006)}$$

Modeling roughness during heteroepitaxial growth

Good for modeling thin film growth & roughness evolution (θ =fraction covered)



Thickness fringes - compare to STO (green)

changes in electron density and/or lattice parameter

I Ouc PTO/STO with c_{film} =4.1 Å, a_{sub} =3.905 Å, ξ = 3.905 Å (both ρ and c)



Thickness fringes - compare to STO (green)

changes in electron density and/or lattice parameter

I Ouc PTO/STO with c_{film} =4.1 Å, a_{sub} =3.905 Å, ξ = 3.905 Å (both Δρ and Δc) I Ouc STO/STO with c_{film} =4.1 Å, a_{sub} =3.905 Å, ξ = 3.905 Å (just Δc)



Thickness fringes - compare to STO (green)

changes in electron density and/or lattice parameter

I 0 uc PTO/STO with c_{film} =3.905 Å, a_{sub} =3.905 Å, ξ = 3.905 Å (just Δρ)



Thickness fringes - compare to STO (green)

changes in electron density and/or lattice parameter

I Ouc PTO/STO with c_{film} =3.905 Å, a_{sub} =3.905 Å, ξ = 3.905 Å (just Δρ) I Ouc STO/STO with c_{film} =3.905 Å, a_{sub} =3.905 Å, ξ = 3.93 Å (just ξ)



Experimental verification - hybrid MBE + MOCVD

stoichiometric STO on STO with different $\boldsymbol{\xi}$



purposefully non-stoichiometric STO



reflectivity is ~ insensitive to the stoichiometry



LeBeau et al., Appl. Phys. Lett. 95, 142905 (2009)

A few words on grazing incidence studies

Index of refraction

 $n = I - \delta + i\beta$ where δ related to mass density and f'(Q) $n \equiv 1 - \frac{2\pi \rho_{at} r_0}{k^2} \left\{ f^0(0) + f' + i f'' \right\}$ β related to absorption and f''(Q)critical angle for total external reflection: $\alpha_c = (2\delta)^{1/2}$ Diffracted ~ typically a few tenths of a degree Incident Reflected $2\theta_{\rm B}$ Ø Refracted

M. Toney and S. Brennan, Phys. Rev. B. 39, 7963 (1989)

In-plane peaks $(L \sim 0)$: grazing incidence diffraction



G. Renaud, Surf. Sci. Rep. 32, 1 (1998)



(L ~ 0.05: also near α_c but exiting the sample)

Growth of Pb(Zr,Ti)O₃ films on SrTiO₃ (001)



In-plane peaks ($L \approx 0$): grazing incidence diffraction





In-plane peaks ($L \sim 0$): surface reconstructions





This is actually the layer under the PbO surface









A. Munkholm et al., Phys. Rev. Lett. 88, 016101 (2001)

In-plane peaks ($L \sim 0$): surface reconstructions



Grazing incidence

at and below α_c ,

- penetration depth ~ 30 Å ("perfect" reflection below α_c)
 - can work at α_c for in-plane diffraction studies [you get a relative intensity enhancement]
 - e.g., H 0 0 scan [grazing incidence + grazing exit] often for studies of in-plane reconstruction peaks
 - can also do CTR-scans on ultrathin films (e.g., I-5 unit cells) but out-of-plane scans are shifted in L
 - can improve signal from intensity boost at α_c from total external reflection + large footprint
- but you don't need to vary penetration depth to get depth dependent info
 from single crystals: modeling or solving phase problem also does it



Grazing incidence: effects of refraction

In-plane diffraction (L \sim 0): no problem But if you stay at α_c to run up a CTR or SR:

diffracted beam appears at altered L-position due to refraction



Angular shift in out-of-plane direction:

$$2 \Delta \theta = 2\theta - 2\theta_B$$

= $\phi - \frac{(k'_r)_z}{(k'_r)_x}$
 $\approx \phi - \frac{1}{\sqrt{2}} \{ [(\phi^2 - \phi_c^2)^2 + 4\beta^2]^{1/2} - \phi_c^2 + \phi^2 \}^{1/2} \}$

So in general, we like to keep $\alpha \sim 1^{\circ}$

M. F. Toney and S. Brennan, Phys. Rev. B 39, 7963 (1989)



Direct Methods

- Trying to avoid fitting
- Assumes coherent scattering (e.g., single crystal)
- if large single crystal -- doesn't need APS-U
- if small single crystal -- needs APS-U
- direct methods will become routine

Note: APS-U will make 3D Fourier transform easier

ID Fourier transform



3D Fourier transform





D. D. Fong et al. MRS Bulletin **35,** 504 (2010)

Direct methods Sub

Subsection

Example: 4-unit-cell PbTiO₃ / SrTiO₃ (001)



Growth of epitaxial ferroelectric PbTiO₃ by metal organic chemical vapor deposition (MOCVD)





D. D. Fong, Y. Yacoby, et al., Phys. Rev. B, **71**, 144112 (2005)

Fourier cycling

Need to assign some phases (imaginary parts) to F(Q) to start **Ideally:** Im



Fourier cycling

Need to assign some phases (imaginary parts) to F(Q) to start **Ideally:** Im



But usually:



Fourier cycling

So force it to be real & positive (zero the imaginary & negative parts)



Fourier cycling — now FT





Fix the amplitude of F(Q) to match the data

This corresponds to error corrections in reciprocal space: $\Delta F(Q)$

Can be shown that these are "minimum-change" operations such that the sum of the squared errors can be minimized through an iterative algorithm (Fourier cycling) R.W. Gerchberg and W.O. Saxton, "A practical algorithm for the determination of the phase from image and diffraction plane pictures," Optik **35**, 237 (1972)

J. R. Fienup, Opt. Letters 3, 27 (1978); Appl. Opt. 21, 2758 (1982)



Direct methods

Subsection

Oversampling

How much data do you need to take to reconstruct ρ_{el} ?



Need to sample by at least $\Delta Q = 1/(2a)$ in reciprocal space, but this assumes we can access the complex structure factor (amplitude and phase)

- since we can only sample the structure factor amplitude, we need to sample by $\Delta Q = I/(4a)$
- for a thin film, this is $\Delta Q = I/(2t)$, so for a 2 unit cell film, we need to sample at a spacing of $\Delta L \sim 0.25$
- Not a problem for CTRs (continuous): we typically sample at least twice this (~ 7 points per thickness fringe) - **oversampling** (can only be done along L for thin films)
- We can do this for multiple CTRs

D. Sayre, Struct. Chem. **13**, 81 (2002)

Direct methods

COherent Bragg Rod Analysis (COBRA): Example La_{2-x}Sr_xCuO₄ / LaSrAlO₄(001)

Measure all independent rods $F_{HK}(L)$

$$F(\mathbf{q}) = \sum_{j=1}^{N_{uc}} f_j(q) e^{i\mathbf{q}\cdot\mathbf{r}_j}$$

$$F_{HKL} = f_A e^{\pi i(H+K)} + f_B e^{\pi i(L)}$$

$$+ f_O \left[1 + e^{\pi i(K+L)} + e^{\pi i(H+K+L)} \right]$$



E.g., for 4mm perovskite symmetry:

- 3 independent rods
- (even, even, *L*)
- (odd, odd, *L*)
- (odd, even, *L*)
- Typically more rods are measured for reduced error (at least 6 offspecular + specular)
 - specular is often different (nonregistered surface layers can modify the specular rod)

U

Real space structures for single and bilayer films

$La_{2-x}Sr_{x}CuO_{4}$ on $LaSrAIO_{4}(001)$



H. Zhou et al., PNAS**IO**, 8103 (2010)

LSAO Substrate

Section Subsection

Another way: DFT + fitting

To account for disorder, defects, and non-equilibrium processes, we combine insights from theory and experiment into one fitting procedure

$$R^{2} = \chi^{2} + \chi_{res}^{2} + \frac{1}{2} \frac{\kappa}{kT} \sum_{I} (\zeta_{I} - Z_{I})^{2}$$

Experiment

Fit residual R^2 for non-linear least squares fitting of atomic positions $\{\zeta_I\}$, Debye-Waller factors $\{\sigma_I\}$, and occupancies $\{\theta_I\}$ of each atom.

• Experimental chi-squared χ^2 constrains predicted structure factor $|F(\zeta,\sigma,\theta)|^2$ to measured structure factor $|F_{exp}|^2$.

- Resonant (χ^2_{res}) and non-resonant (χ^2) data may both be included in residual.
- Penalty function prevents atomic positions $\{\zeta_I\}$ from varying significantly from the DFT predicted positions $\{Z_I\}$.
- κ/kT determines weight of the penalty function compared to χ^2 with effective spring constant κ and temperature dependent energy scale kT.

DFT

Section

Subsection

Another way: DFT + fitting: here the SrTiO₃ (001) surface

Chief advantage -- you get DFT-based information as well - S.Y. Cook et al., Sci. Adv.5, eaav0764 (2019)

SXRD geometry

T.T. Fister & D. D. Fong in Thin Film Metal-Oxides, Springer (2010)

SXRD geometry + a lot of equipment

Can do a lot by combining SXRD + in situ
Need to have the proper geometry

Six-circle geometry (4S+2D)

Note the laboratory coordinate system (x,y,z)

Q is defined by

- $\theta = \omega = Bragg$ angle of Q (=4 π sin(θ)/ λ) (longitudinal angle from xz-plane toward y)
- v = qaz = azimuthal angle for Q (from z-axis)
- n (sample reference vector often assumed equal to the sample normal)
- α = incident angle (longitudinal angle from xz-plane toward y)
- ϕ = naz = azimuthal angle for n (from z-axis)
- typically, n = sample normal
- naz = 0: sample normal along z
- naz = 90°: sample normal along x

H.You, J.Appl. Cryst. **32,** 614 (1999)

T.T. Fister et al., J. Appl. Cryst. 46 (2013)

X-ray beam

Six-circle geometry

First, relate \mathbf{h} (i.e., Q) to (x, y, z) [4S] Next, relate $\mathbf{k}_{\mathbf{f}}$ to (x, y, z) [2D] Next, by definition: at diffraction condition: $\mathbf{h} = \mathbf{k}_{\mathbf{f}} - \mathbf{k}_{\mathbf{i}}$

4S

$$\mathbf{h} \stackrel{\mathbf{B}}{\longrightarrow} \mathbf{h}_{c} \stackrel{\mathbf{U}}{\longrightarrow} \mathbf{h}_{\phi} \stackrel{\Phi}{\longrightarrow} \mathbf{h}_{\chi} \stackrel{\mathbf{X}}{\longrightarrow} \mathbf{h}_{\eta} \stackrel{\mathbf{H}}{\longrightarrow} \mathbf{h}_{\mu} \stackrel{\mathbf{M}}{\longrightarrow} \mathbf{h}_{M},$$

$$\mathbf{\Phi} = \begin{pmatrix} \cos \phi & \sin \phi & 0 \\ -\sin \phi & \cos \phi & 0 \\ 0 & 0 & 1 \end{pmatrix},$$

$$\mathbf{X} = \begin{pmatrix} \cos \chi & 0 & \sin \chi \\ 0 & 1 & 0 \\ -\sin \chi & 0 & \cos \chi \end{pmatrix},$$

$$\mathbf{H} = \begin{pmatrix} \cos \eta & \sin \eta & 0 \\ -\sin \eta & \cos \eta & 0 \\ 0 & 0 & 1 \end{pmatrix},$$

$$\mathbf{H} = \begin{pmatrix} 1 & 0 & 0 \\ 0 & \cos \mu & -\sin \mu \\ 0 & \sin \mu & \cos \mu \end{pmatrix}.$$

$$\mathbf{h}_{M} = \mathbf{M}\mathbf{H}\mathbf{X}\mathbf{\Phi}\mathbf{U}\mathbf{B}\mathbf{h}$$

2D

$$\mathbf{k}_{0}^{f} \xrightarrow{\Lambda} \mathbf{k}_{\delta}^{f} \xrightarrow{\Pi} \mathbf{k}_{\nu}^{f}$$

$$\Delta = \begin{pmatrix} \cos \delta & \sin \delta & 0 \\ -\sin \delta & \cos \delta & 0 \\ 0 & 0 & 1 \end{pmatrix},$$

$$\Pi = \begin{pmatrix} 1 & 0 & 0 \\ 0 & \cos \nu & -\sin \nu \\ 0 & \sin \nu & \cos \nu \end{pmatrix}.$$

$$\mathbf{k}_{\nu}^{f} = k \Pi \Delta \begin{pmatrix} 0 \\ 1 \\ 0 \end{pmatrix} = k \begin{pmatrix} \sin \delta \\ \cos \nu \cos \delta \\ \sin \nu \cos \delta \end{pmatrix}$$

at diffraction condition:

$$\mathbf{h}_{M}=\mathbf{Q}_{L},$$

where $h_M = MHX\Phi UBh$

and
$$\mathbf{Q}_L = \mathbf{k}_{\nu}^f - \mathbf{k}_L^i = (\mathbf{\Pi} \mathbf{\Delta} - \mathbf{I}) \begin{pmatrix} 0 \\ k \\ 0 \end{pmatrix} = k \begin{pmatrix} \sin \delta \\ \cos \delta \cos \nu - 1 \\ \cos \delta \sin \nu \end{pmatrix}$$

Six-circle geometry

Put everything into software

- spec -- <u>http://www.certif.com</u>
- modes for six-circle, four-circle, etc.
- then you can type (effectively) "go to 202; scan along 20L"

Why do you need a six-circle?

- you can keep a constant x-ray footprint on the sample
- nice for L ~ 0 work
- nice for easier geometrical corrections

N. Jedrecy, J. Appl. Cryst. 33, 1365 (2000)

Geometrical corrections

Integrated intensity often came from a ϕ -scan+point detector

Corrected integrated intensity

E.Vlieg, J.Appl. Cryst. 30, 532 (1997)

• With 2D detectors (like Pilatus), it is easier, since we don't rock sample

C. M. Schlepütz et al., Acta Cryst. A 61, 418 (2005)

Example of SXRD + X-ray photon correlation spectroscopy

Section Subsection

In situ SXRD with gas control system (N₂ \leftrightarrow O₂, T)

Time-dependent speckle reveals dynamics

Dynamics and time correlations (at any **Q**)

state of material varies from A to B to C to D

SrCoO_x/LSAT (001) phase equilibrium

SrCoO_x/LSAT (001): Kinetics in N₂

Intensity of 001/2: stable with time

SrCoO_x/LSAT (001): Dynamics in N₂

Intensity of 001/2: stable with time

Dynamics of 001/2: fluctuating with time

N₂ at 350°C

Real space: vacancy fluctuations at 350°C

partially correlated in time

Section Subsection

Temperature dependence

Questions?

https://forms.office.com/g/MdYE7snFqs

NXS Lecture - Dillon Fong: "Surface and Interface Scattering"

